

# Si(111) strained layers structure on Ge(111) surface

R. Zhachuk,<sup>1</sup> J. Coutinho,<sup>2</sup> V. Cherepanov,<sup>3,4</sup> B. Voigtlander<sup>3,4</sup>

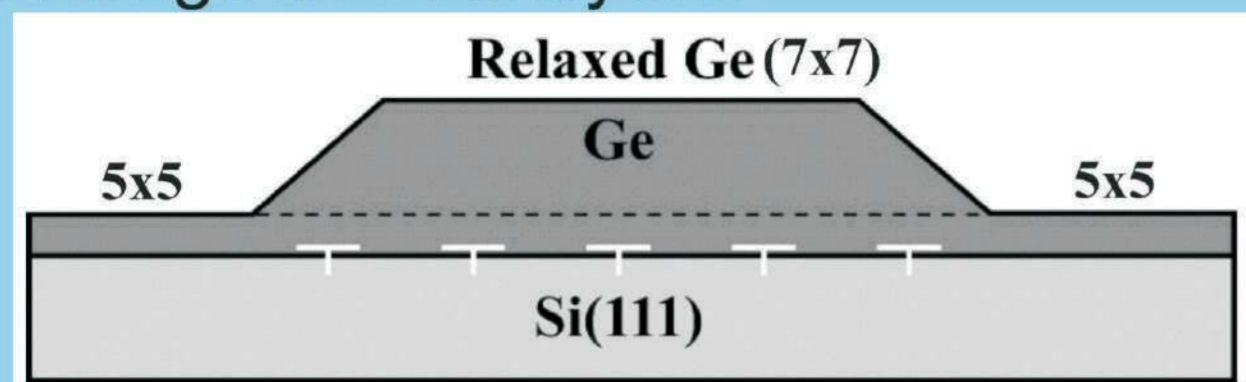
<sup>1</sup>Institute of Semiconductor Physics, pr. Lavrentyeva 13, Novosibirsk 630090, Russia

<sup>2</sup>I3N, University of Aveiro, Aveiro, Portugal

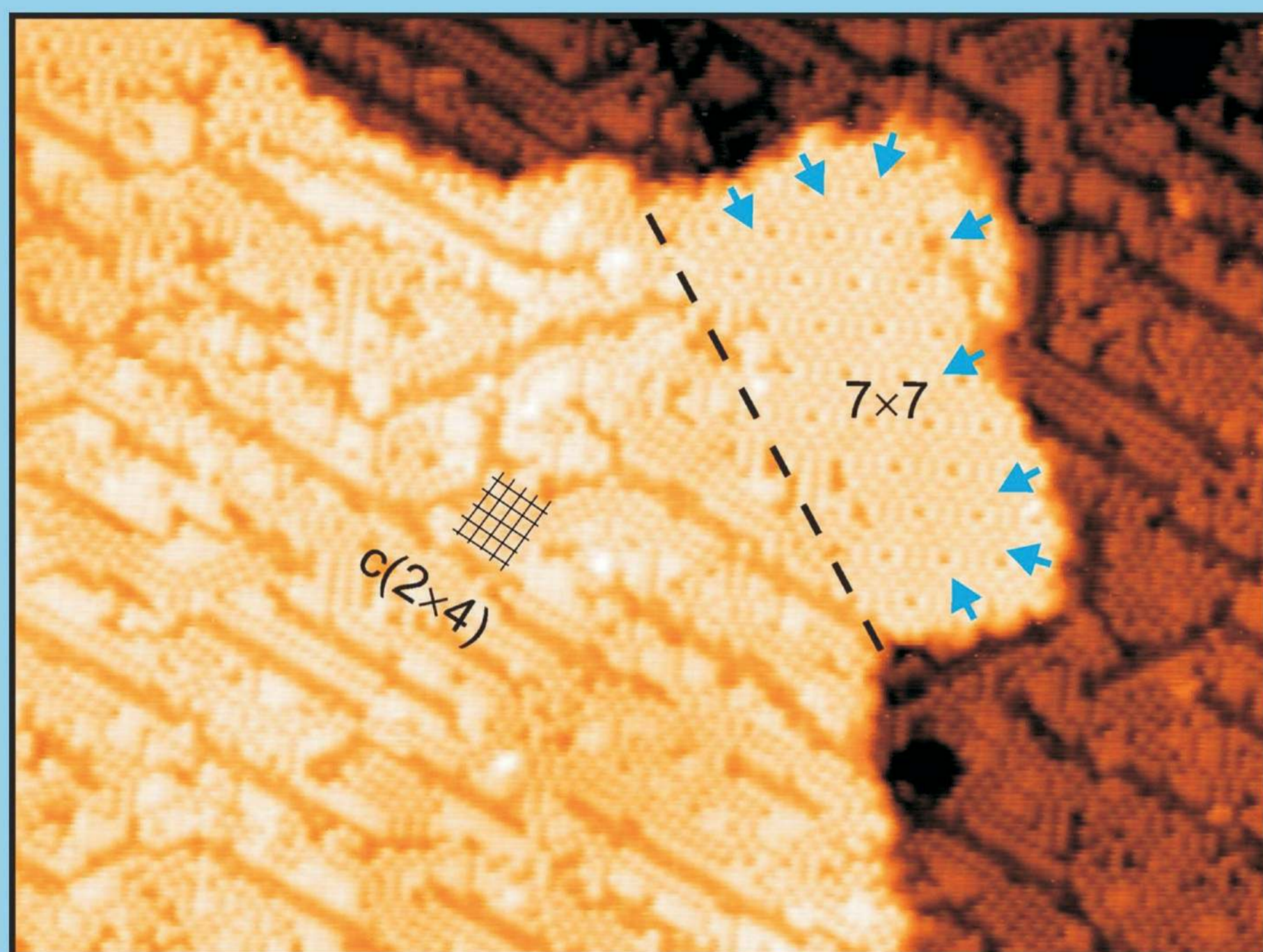
<sup>3</sup>Peter Grünberg Institut (PGI-3), Forschungszentrum Jülich, 52425 Jülich, Germany

## Experiment:

- Ge Islands as substrate:  $H = 150 \text{ \AA}$ ,  $L = 5000 \text{ \AA}$ .
- $T_{\text{ads}} = 400\text{-}550^\circ\text{C}$ .
- Si coverage is 2-4 bilayers.



## STM image of the Si/Ge(111) surface



2 bilayers of Si on Ge(111),  $T_{\text{ads}} = 540 \text{ C}$

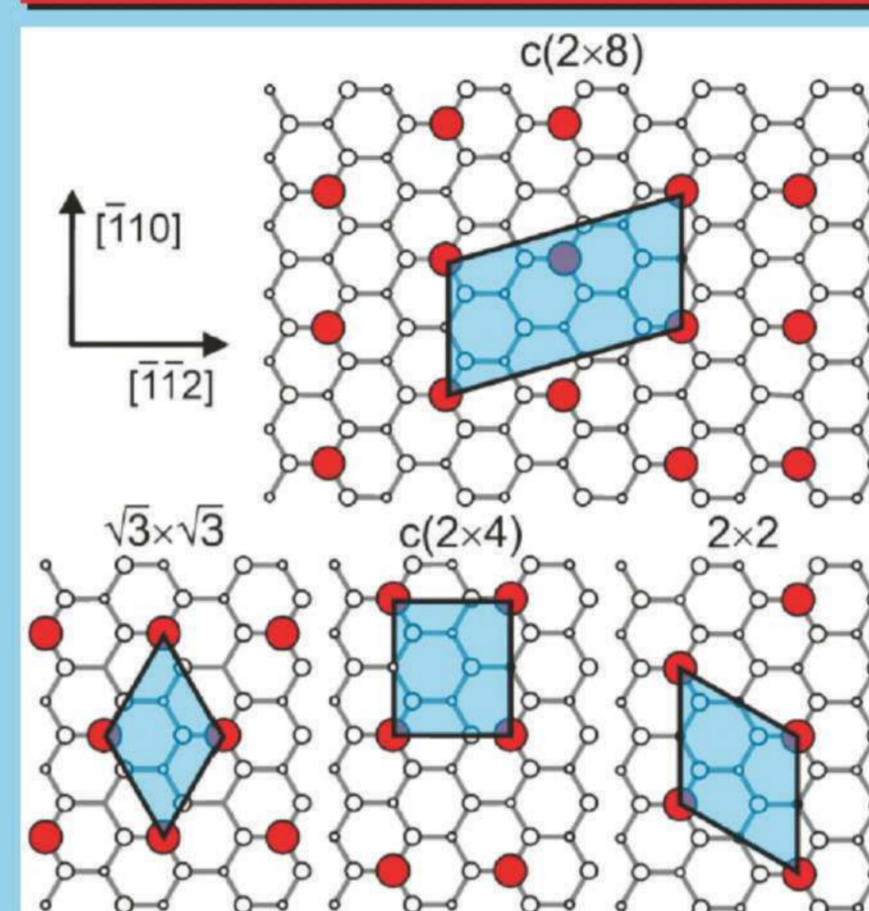
**Motivation:** calculations show that Si(111) and Ge(111) surface structure undergo the following transformation when surface strain is applied (from left to right: tensile strain, from right to left: compressive strain):

[DAS structures]  $\longleftrightarrow$  [adatom-based structures]

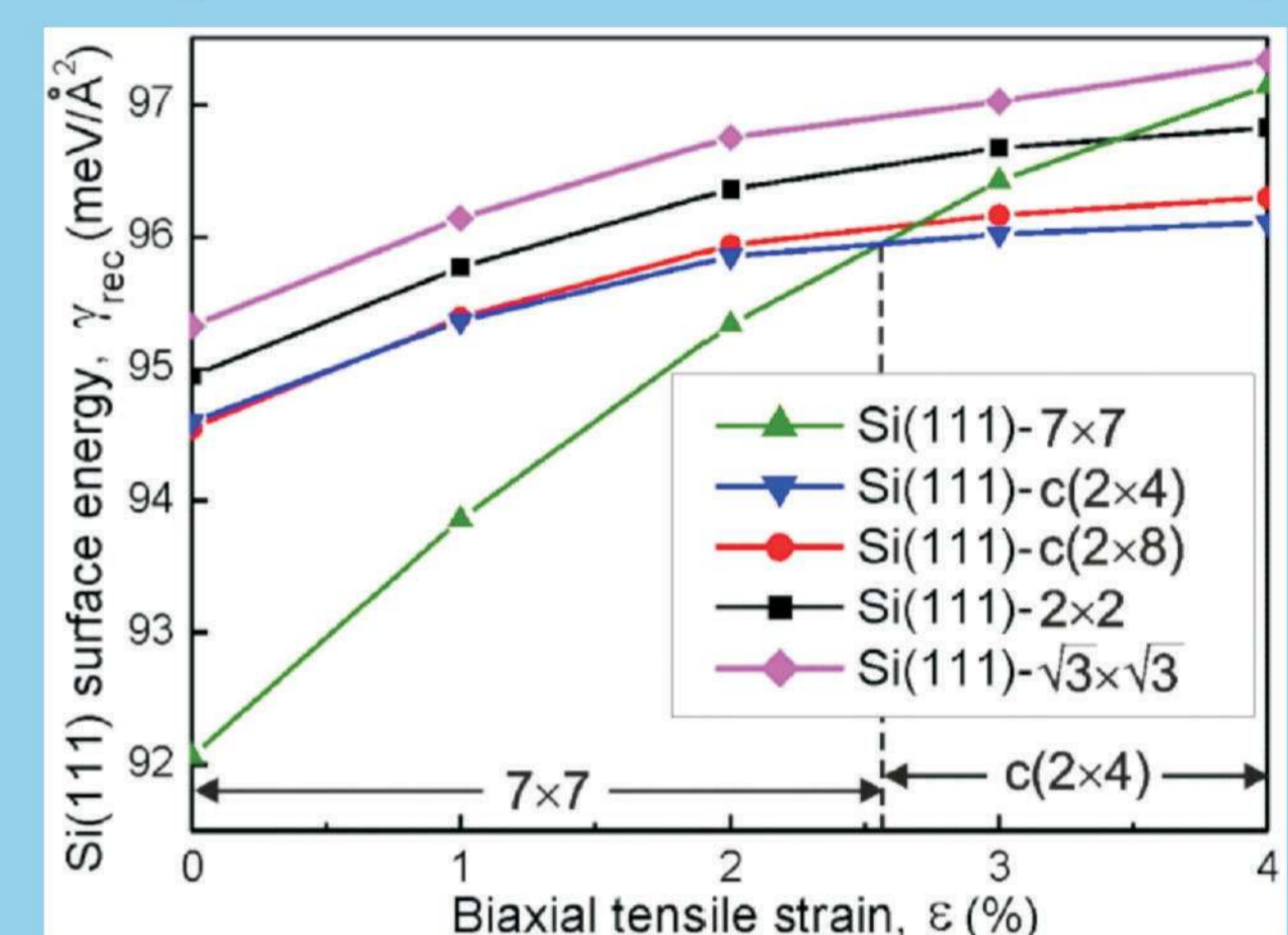
**Aim:** solve the atomic structure of tensile strained Si layers, formed during Si/Ge(111) growth. **Methods:** LEED, STM (Omicron), DFT (Siesta).

## 1. No Ge/Si intermixing

### Adatom-based structures

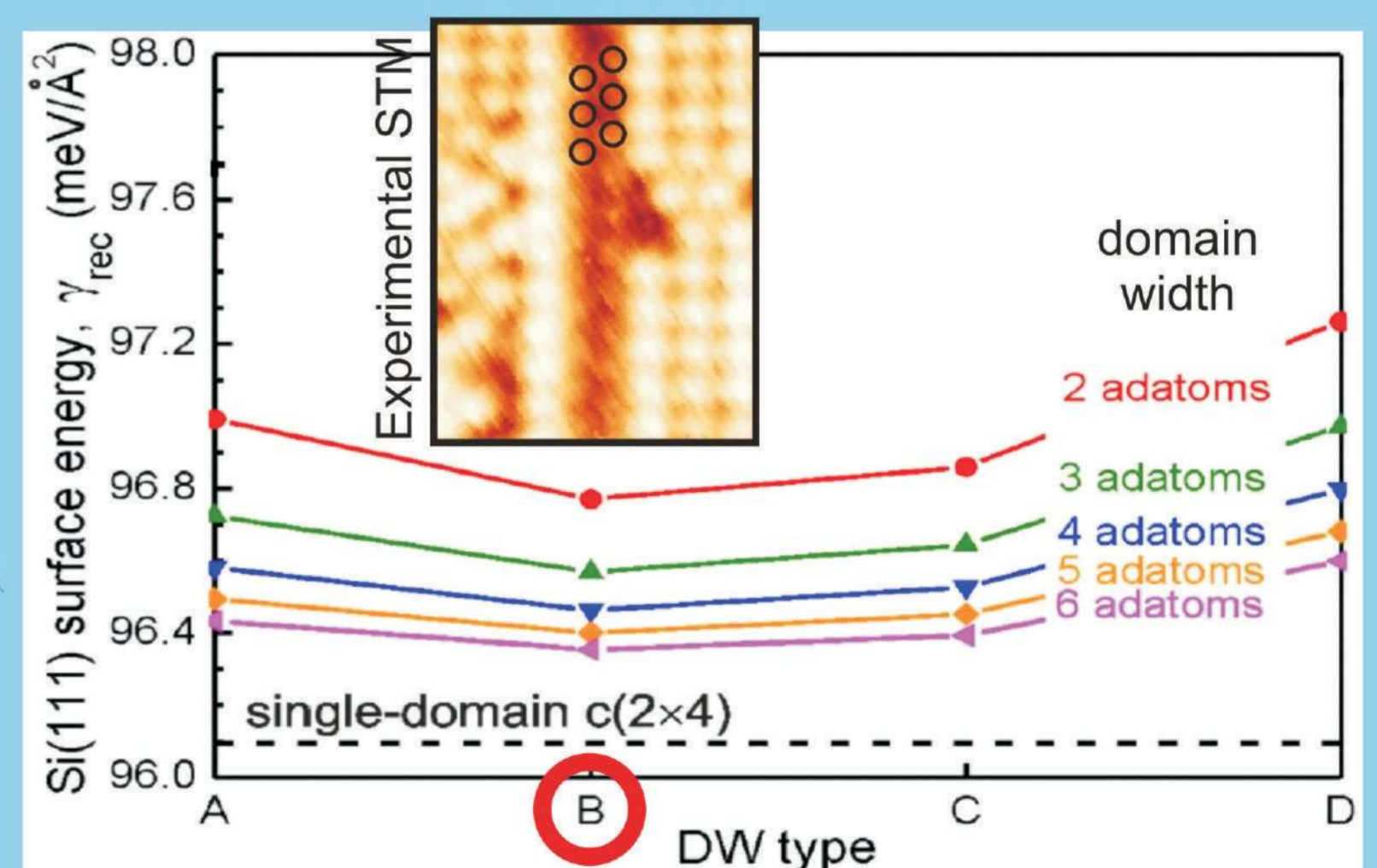
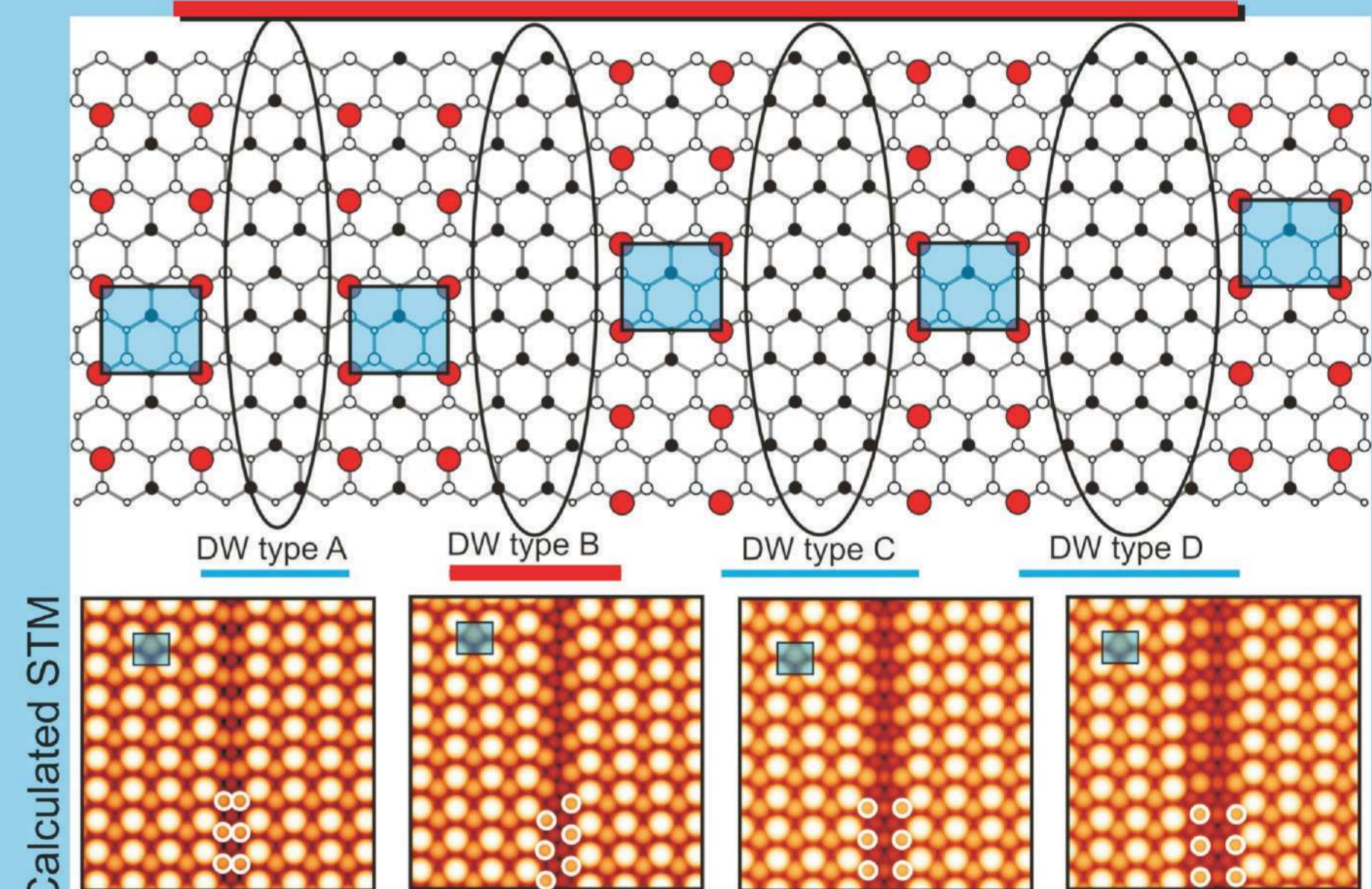


### Si(111) phase diagram

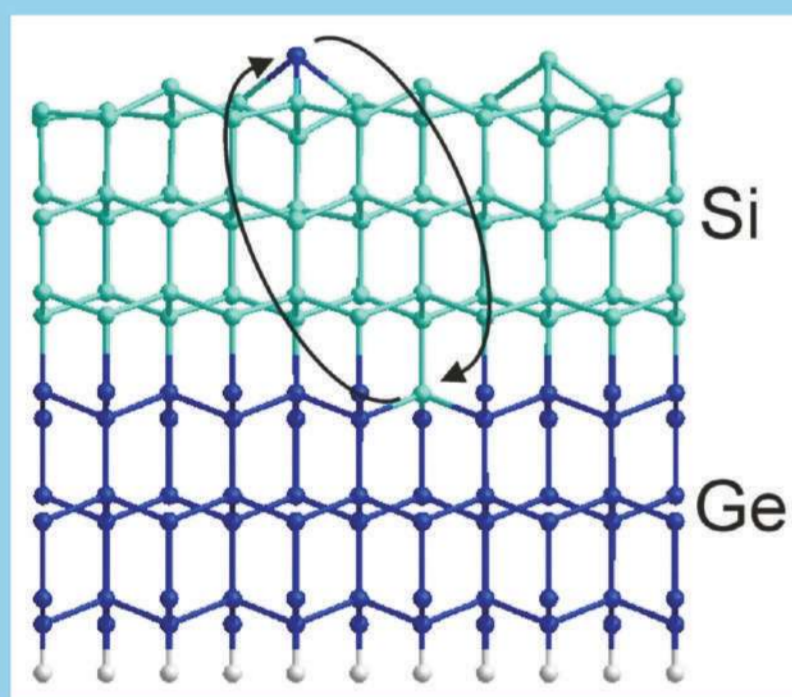


### Atomic structure of domain walls (DW)

Domain walls do not form when no Ge and Si intermixing is considered, since they do not lead to relaxation of Si layers!



## 2. Ge/Si intermixing



Surface structure	Surface energy (meV/A <sup>2</sup> )	
	no intermixing	intermixing
c(2x4)	96.1	82.9
c(2x4) + DW	96.6	82.4

(DW type "B", width is 3 adatoms)

- Si and Ge atoms are undistinguishable in STM.
- Energy gain is 0.4 eV per Si-Ge pair when Ge substitutes Si atom with dangling bond (adatoms or rest-atoms). This energy gain is due to Si bonds being stronger than that of Ge.
- Density of dangling bonds in DW is twice higher than in c(2x4) structure.
- DW is energetically favorable when Si/Ge intermixing is considered. Ge local concentration in DW must be higher than that in the c(2x4) structure (i.e. nanowires).

## Conclusions:

- 1) Under tensile strain the Si(111) surface structure changes 7x7 (DAS)  $\rightarrow$  c(2x4) (adatom-based) in agreement with calculations.
- 2) Atomic models of the c(2x4) structure and its domain walls are developed.
- 3) The reason for c(2x4) domain walls formation is intermixing of Ge and Si atoms.